Ifw BTO/SBRD1 (00 00

Approved for use through 07/31/2006. OMB 0651-0031 U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it displays a valid OMB control number Application Number 10/646,533 Filing Date August 22, 2003 TRANSMITTAL First Named Inventor **FORM** et al Kenneth COLLINS, Art Unit 2813 **Examiner Name** Jack S. Chen Attorney Docket Number 006915 P02 Total Number of Pages in This Submission **ENCLOSURES** (Check all that apply) After Allowance Communication to TC Fee Transmittal Form Drawing(s) Appeal Communication to Board Licensing-related Papers Fee Attached of Appeals and Interferences Appeal Communication to TC Petition (Appeal Notice, Brief, Reply Brief) Amendment/Reply Petition to Convert to a Proprietary Information After Final **Provisional Application** Power of Attorney, Revocation Status Letter Affidavits/declaration(s) Change of Correspondence Address Other Enclosure(s) (please Identify Terminal Disclaimer below): Extension of Time Request Request for Refund Express Abandonment Request CD, Number of CD(s) Information Disclosure Statement Landscape Table on CD Certified Copy of Priority Remarks Document(s) Reply to Missing Parts/ Incomplete Application Reply to Missing Parts under 37 CFR 1.52 or 1.53 SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT Firm Name Law Office of Robert M. Wallace Signature Printed name Robert M. Wallace Reg. No. Date 29,119 CERTIFICATE OF TRANSMISSION/MAILING I hereby certify that this correspondence is being facsimile transmitted to the USPTO or deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on the date shown below: Signature helly Hart Typed or printed name

This collection of information is required by 37 CFR 1.5. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.11 and 1.14. This collection is estimated to 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

CERTIFICATE OF MAILING
I hereby certify that this paper and every
paper referred to therein as being suchased
is deposited with the U.S. Fund during
as first class and, persons propell, in
an everype addressed to Chambellone
for Paness, P.O. Box 1889, American M. 22213-1485

an AINENGER II J. Chambellone

MINENGER II J. Chambellone
Date

NOV 1 4 2005

PATENT

Attorney Docket No. 006915 P02 RW Ref. No. APM/001-02-CP1-1-2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

<pre>In re Application of Kenneth COLLINS, et al.)</pre>		
)	Group Art	Unit: 2813
Entitled: PLASMA IMMERSION ION)	-	
IMPLANTATION PROCESS USING A PLASMA)	Examiner:	Jack S. Chen
SOURCE HAVING LOW DISSOCIATION AND)		
LOW MINIMUM PLASMA VOLTAGE)		
)		
Serial No.: 10/646,533)		
)		
Filing Date: August 22, 2003)		

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97(c) PRIOR TO FINAL ACTION AND WITHIN THREE MONTHS OF RECEIVING FOREIGN PATENT OFFICE COMMUNICATION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Attached hereto is Form PTO-1449 listing documents believed relevant to the subject application. It is respectfully requested that these documents be made of record and an initialed copy of each form be returned to the undersigned.

I hereby certify that each item of information contained in this Information Disclosure Statement was cited in a communication (a copy of which is attached) from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.

It is believed that this disclosure complies with the requirements of 37 CFR 1.56 and the Manual of Patent Examining Procedures Section 707.5(b). If for some reason the Examiner considers otherwise, it is respectfully requested that the undersigned be called so that any deficiencies can be remedied.

A copy of each foreign patent document and/or non-patent

literature is enclosed. Some of the documents may have markings on them. No significance is meant to be attached to the markings. These documents are not necessarily analogous art.

Respectfully submitted,

Rokenthulser

Robert M. Wallace

Registration No. 29,119

Attorney for Applicants Customer No. 000044843

Robert M. Wallace Patent Attorney 2112 Eastman Avenue, Suite 102 Ventura, CA 93003 (805) 644-4035

2

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Sheet 1 of 1

Application Number:

10/646,533

Filing Date:

August 22, 2003

First Named Inventor: Group Art Unit:

Kenneth COLLINS, et al. 2813

Examiner Name:

Jack S. Chen

Attorney Docket Number:

006915 P02

U. S. PATENT DOCUMENTS

				,	T	· · · · · · · · · · · · · · · · · · ·
Examiner Initials	Document No	Publication Date	Name of Patentee or Applicant of Cited Document	Class	Subclass	Filing Date
•	US-6,395,150 B1	05-28-2002	CAN CLEEMPUT ET AL.	204	192.37	04-01-1998
	US-6,413,321 B1	07-02-2002	KIM ET AL.	118	725	12-07-2000
•	US 2003/0013260 A1	01-16-2003	GOSSMAN ET AL.	438	301	07-16-2001
	US 2003/0085205 A1	05-08-2003	LAI ET AL.	219	121.43	04-20-2001
. 1						
						3

FOREIGN PATENT DOCUMENTS

Examiner Initials	Foreign Patent Document	Publication Date	Country	Name of Patentee or Applicant of Cited Document	Translation? (Yes/No/n/a)
	EP 1 158 071 A2	28.11.2001	EUROPE	APPLIED MATERIALS, INC.	N/A
	JP 070455542	14.02.1995	JAPAN	MATSUSHITA ELECTRIC IND CO LTD	N/A
	JP 2000150908	30.05.2000	JAPAN	SEMICONDUCTOR ENERGY LAB CO LTD	N/A
		<u> </u>			

Examiner Initials

NON PATENT LITERATURE DOCUMENTS

Hu, C.-K., et al., "A process for improved Al(cu) reactive ion etching", Journal of Vacuum Science and Technology", May 1, 1989, pp. 682-685, Vol. 7, No. 3, American Institute of Physics, New York, U.S.

Examiner's Signature:

Date Considered:

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.